



IFW 1765

Docket No.: 10191/1614

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors : Richard SPITZ et al.
Serial No. : 09/720,720
Filed : February 28, 2001
For : METHOD FOR ELIMINATING DEFECTS IN SILICON
ELEMENTS THROUGH SELECTIVE ETCHING
Examiner : TRAN, Binh
Art Unit : 1765
Confirmation No. : 3872

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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Date: September 7, 2006

Reg. No. 36,197

Signature: _____

Jong H. Lee

AMENDMENT

SIR:

This Amendment addresses the Office Action mailed June 22, 2006, and it is respectfully requested that the above-identified application be amended as follows.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.